

U.S. Department of Commerce, Patent and Trademark Office					Atty Docket No.		Serial No.	
					M-15317 US		10-1754 365	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT					Applicant(s)			
(Use several sheets if necessary)					Yin S. Tang			
					Filing Date		Group	
					1/08/2004		2873	
U.S. Patent Documents								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
D/S	AA	4,541,727	09/17/1985	Rosenthal	368	232		
D/S	AB	6,129,866	10/10/2000	Hamanaka et al.	264	1.7		
D/S	AC	6,335,828	01/01/2002	Hashimoto et al.	359	443		
D/S	AD	6,582,988	06/24/2003	Hsiao et al.	438	70		
D/S	AE	6,654,174	11/25/2003	Huang	359	619		
	AF							
Foreign Patent Documents								
							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	AG							
	AH							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
D/S	AI	B. Volckaerts et al., <u>The Fabrication of Cylindrical Micro-Lens Arrays with Deep Lithography with Protons</u> , Cyclotron Department VUB, Laarbeeklaan 103, 1090 Brussels, Belgium, 2002.						
	AJ	DAVID SPECTOR PRIMARY EXAMINER						
Examiner	[Signature]		Date Considered 2/10/2005					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.								